



IFC

Docket No.: H6808.0024/P024
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Hiroshi Miyai et al.

Application No.: 10/669,253

Confirmation No.: N/A

Filed: September 25, 2003

Art Unit: N/A

For: AN INSPECTION METHOD AND
APPARATUS USING AN ELECTRON
BEAM

Examiner: Not Yet Assigned

STATUS INQUIRY

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

It is respectfully requested that the attorney named below be advised of the status of the above-identified application. Please advise us of when we might expect to receive a Filing Receipt from the Patent and Trademark Office.

Dated: June 23, 2004

Respectfully submitted,

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